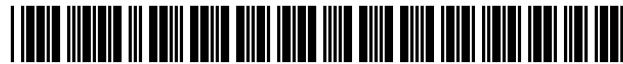


EXHIBIT F



US006836691B1

(12) **United States Patent**
Stirton

(10) **Patent No.:** **US 6,836,691 B1**
(45) **Date of Patent:** **Dec. 28, 2004**

(54) **METHOD AND APPARATUS FOR
FILTERING METROLOGY DATA BASED ON
COLLECTION PURPOSE**

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(*) Notice: Subject to any disclaimer, the term of this
patent is extended or adjusted under 35
U.S.C. 154(b) by 0 days.

(21) Appl. No.: **10/427,620**

(22) Filed: **May 1, 2003**

(51) Int. Cl.⁷ **G06F 19/00**

(52) U.S. Cl. **700/108; 702/85**

(58) Field of Search 700/108, 95, 110,
700/117; 702/85; 709/108, 320; 712/228;
714/25, 54; 438/12; 345/708

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Primary Examiner—Leo Picard

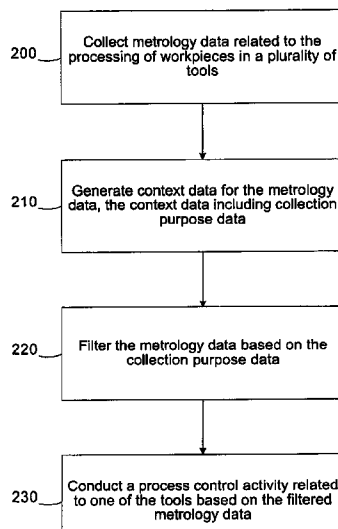
Assistant Examiner—Carlos R. Ortiz

(74) *Attorney, Agent, or Firm*—Williams, Morgan &
Amerson

(57) **ABSTRACT**

A method includes collecting metrology data related to the
processing of workpieces in a plurality of tools. Context data
for the metrology data is generated. The context data
includes collection purpose data. The metrology data is
filtered based on the collection purpose data. A process
control activity related to one of the tools is conducted based
on the filtered metrology data. A system includes at least one
metrology tool, a computer, and a process controller. The
metrology tool is configured to collect metrology data
related to the processing of workpieces in a plurality of
tools. The computer is configured to generate context data
for the metrology data, the context data including collection
purpose data. The process controller is configured to filter
the metrology data based on the collection purpose data and
conduct a process control activity related to one of the tools
based on the filtered metrology data.

20 Claims, 2 Drawing Sheets



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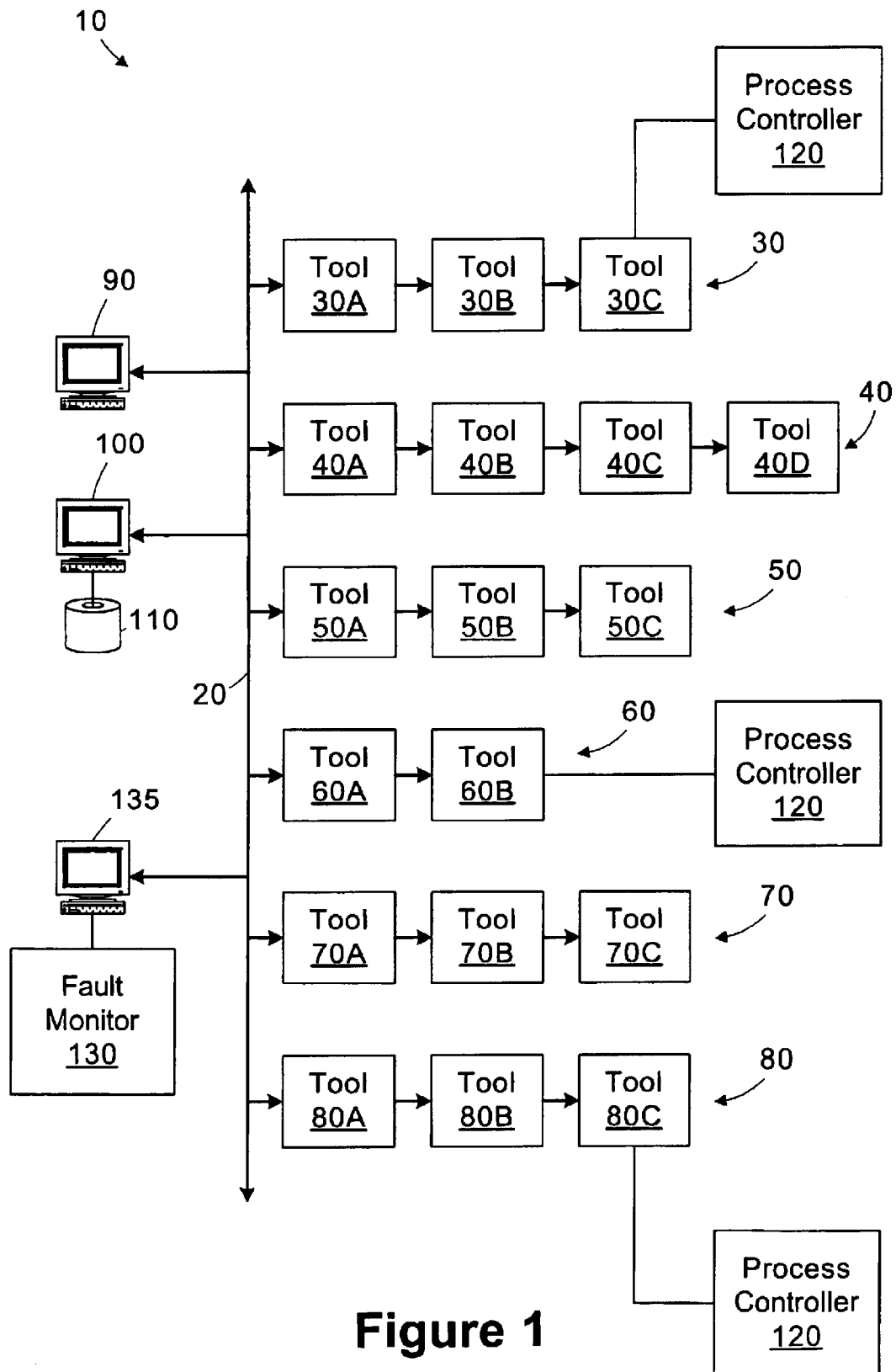
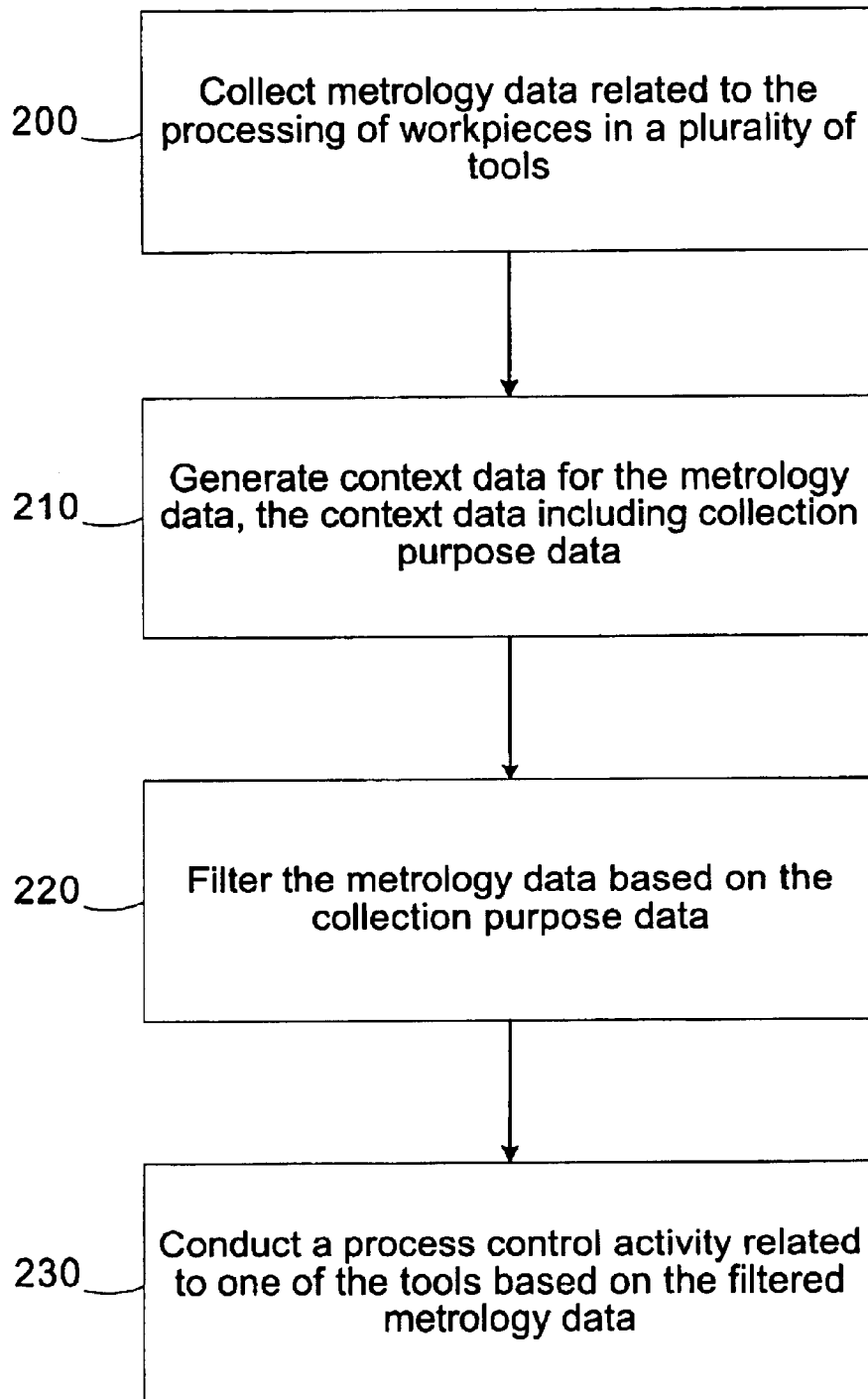


Figure 1

**Figure 2**

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